

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1398		SERIAL NO. 09/536,037	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Weimin Li, et al.			
				FILING DATE March 27, 2000		GROUP 2822	

U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
TMT	AA	6,503,818 B1	01/2003	Jang	438	584	
	AB	6,486,061 B1	11/2002	Xia et al.	438	680	
	AC	6,486,057 B1	11/2002	Yeh et al.	438	633	
	AD	6,465,372 B1	10/2002	Xia et al.	438	787	
	AE	6,444,593 B1	09/2002	Ngo et al.	438	788	
	AF	6,436,808 B1	08/2002	Ngo et al.	438	623	
	AG	6,435,943 B1	08/2002	Chang et al.	451	28	
	AH	6,429,115 B1	08/2002	Tsai et al.	438	622	
	AI	6,284,677 B1	09/2001	Hsiao et al.	438	783	
	AJ	6,030,901	02/2000	Hopper et al.	438	711	
	AK	6,133,618	10/2000	Steiner	257	646	
	AL	5,994,217	11/1999	Ng	438	636	
	FOREIGN PATENT DOCUMENTS						
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
TMT	AM	8046186	02/1996	Japan			
	AN	8046186	02/1996	Japan			X
	AO	7201716	08/1995	Japan			
	AP	7201716	08/1995	Japan			X
TMT	AQ	8046188	02/1996	Japan			
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)							
TMT	AR	Wolf, S., Silicon Process., V.1 407-413					
TMT	AS	Wolf, S., Silicon Process., Vol 2 48-49 and 435					
	AT						
EXAMINER T. M. Thomas				DATE CONSIDERED 01/06/05			
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1398		SERIAL NO. 09/536,037	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Weimin Li, et al.			
				FILING DATE March 27, 2008		GROUP 2822	

U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
TMT	AA	5,985,519	Kakamu et al.	430	313		
	AB	5,747,388	Kusters et al	438	723		
	AC	5,639,687	Roman et al	438	639		
TMT	AD	5,498,555	Lio	438	302		
	AE						
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	AI						
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FOREIGN PATENT DOCUMENTS								
*Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation		
						Yes	No	
TMT	AM	6232113	08/1994	Japan				
	AN							
	AO							
	AP							
	AQ							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
	AR		
	AS		
	AT		

EXAMINER T. M. Thomas	DATE CONSIDERED 02/06/05
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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE AUG 17 2004			ATTY. DOCKET NO. MI22-1398		SERIAL NO. 09/536,037	
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					FILING DATE March 27, 2000		GROUP 2822	

U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
TMT	AA	6,153,504	Shields et al	438	613		
	AB	4,971,655	Stafano et al	438	592		
	AC	6,498,084 B2	Bergemont	438	593		
	AD	5,036,383	Mori	257	751		
TMT	AE	5,593,741	Ikeeda	427	579		
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	AJ						
	AK						
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FOREIGN PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
TMT	AM	08-045926A	Japan				
TMT	AN	JP8051058	Japan				
TMT	AO	JP63316476	Japan				
TMT	AP	JP8078322	Japan				
TMT	AQ	10-163083	06/1998 Japan				

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)		
TMT	AR	Wolf, S., Silicon Processing for the VLSI ERA. Vol. 3, The Submicron MOSFET p. 635
	AS	
	AT	

EXAMINER <i>T. M. Thomas</i>	DATE CONSIDERED <i>02/06/05</i>
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